

IN THE
UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): Zhizhang (John) Chen et al.

Confirmation No.: 1660

Application No.: 10/085,866

Examiner: Hu, Shouxiang

Filing Date: Feb 27, 2002

Group Art Unit: 2811

Title: EMISSION LAYER FORMED BY RAPID THERMAL FORMATION PROCESS

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL LETTER FOR RESPONSE/AMENDMENT

Sir:

Transmitted herewith is/are the following in the above-identified application:

- (X) Response/Amendment () Petition to extend time to respond
() New fee as calculated below () Supplemental Declaration
(X) No additional fee (Address envelope to "Mail Stop Non-Fee Amendment")
() Other: (fee \$)

CLAIMS AS AMENDED BY OTHER THAN A SMALL ENTITY						
(1) FOR	(2) CLAIMS REMAINING AFTER AMENDMENT	(3) NUMBER EXTRA	(4) HIGHEST NUMBER PREVIOUSLY PAID FOR	(5) PRESENT EXTRA	(6) RATE	(7) ADDITIONAL FEES
TOTAL CLAIMS	7	MINUS	30	= 0	X \$18	\$ 0
INDEP. CLAIMS	2	MINUS	3	= 0	X \$86	\$ 0
[] FIRST PRESENTATION OF A MULTIPLE DEPENDENT CLAIM					+ \$290	\$ 0
EXTENSION FEE	1ST MONTH \$110.00	2ND MONTH \$420.00	3RD MONTH \$950.00	4TH MONTH \$1480.00		\$ 0
OTHER FEES						\$
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$ 0

Charge \$ 0 to Deposit Account 08-2025. At any time during the pendency of this application, please charge any fees required or credit any overpayment to Deposit Account 08-2025 pursuant to 37 CFR 1.25. Additionally please charge any fees to Deposit Account 08-2025 under 37 CFR 1.16 through 1.21 inclusive, and any other sections in Title 37 of the Code of Federal Regulations that may regulate fees. A duplicate copy of this sheet is enclosed.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450.

Date of Deposit: 01/19/2004

Typed Name: Steven P. Fallon

Signature: 

Respectfully submitted,

Zhizhang (John) Chen et al.

By 

Steven P. Fallon

Attorney/Agent for Applicant(s)

Reg. No. 35,132

Date: 01/19/2004



10013802-1

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Zhizhang (John) Chen et al.
Serial No.: 10/085,866
Conf. No.: 1660
Filed: February 27, 2002
For: EMISSION LAYER FORMED BY
RAPID THERMAL FORMATION
PROCESS
Art Unit: 2811
Examiner: Hu, Shouxiang

I hereby certify that this paper is being deposited with the United States Postal Service as FIRST-CLASS mail in an envelope addressed to: Mail Stop Non Fee Amendment Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this date.

1/19/04

Date

Registration No. 35132

F-CLASS.WCM

Appr. February 20, 1998 Attorney for Applicant(s)

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed October 17, 2003, please amend the application as follows:

RECEIVED
JAN 28 2004
TECHNOLOGY CENTER 2800